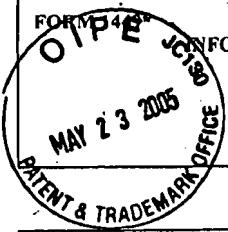


Date Mailed: MAY 20, 2005

Sheet 1 of 1

 <b>INFORMATION DISCLOSURE STATEMENT</b> <b>IN AN APPLICATION</b> <small>(Use several sheets if necessary)</small>	Docket Number:	Application Number:
	10467.43US12	10/751,091
	Applicant: MOECKLY ET AL.	
	Filing Date: 01/02/2004	Group Art Unit: 1755

<b>U.S. PATENT DOCUMENTS</b>						
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>TM</i>	2004/0134967 A1	07/15/2004	Moeckly et al.			
<b>FOREIGN PATENT DOCUMENTS</b>						
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>						
<i>TM</i>		Char, K. et al., "High T <sub>c</sub> superconductor-normal-superconductor Josephson junctions using CaRuO <sub>3</sub> as the metallic barrier," <i>Applied Physics Letters</i> , Vol. 62, No. 2, pp. 196-198 (January 11, 1993)				
<i>TM</i>		Harada, K. et al., "Fabrication of All-High-T <sub>c</sub> Josephson Junction Using As-Grown YBa <sub>2</sub> Cu <sub>3</sub> O <sub>x</sub> Thin Films," <i>Japanese Journal of Applied Physics</i> , Vol. 30, No. 8A, Part 2, pp. L1387-1389 (August 1, 1991)				
<i>TM</i>		Huang, Y. et al., "The effect of microstructure on the electrical properties of YBCO interface-engineered Josephson junctions," <i>Physica C</i> , Vol. 314, pp. 36-42 (1999)				
<i>TM</i>		Makita, T. et al., "Fabrication of Ramp-Edge Junction with NdBa <sub>2</sub> Cu <sub>3</sub> O <sub>y</sub> -Based Interface-Modified Barrier," <i>Jpn. J. Appl. Phys.</i> , Vol. 39, Part 2, No. 7B, pp. L730-L732 (July 15, 2000)				
<i>TM</i>		Makita, T. et al., "Fabrication and Characterization of Y-Ba-Cu-O and Nd-Ba-Cu-O Ramp-Edge Junctions with an Interface-Modified Barrier," <i>IEEE Transactions on Applied Superconductivity</i> , Vol. 11, No. 1, pp. 155-158 (March 2001)				
<i>TM</i>		Moeckly, B. et al., "Interface-Engineered High-T <sub>c</sub> Josephson Junctions," <i>Applied Superconductors</i> , Vol. 6, Nos. 7-9, pp. 317-323 (1998)				

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EXAMINER <i>TM</i> <i>Walter</i>	DATE CONSIDERED <i>01/17/07</i>
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form for next communication to the Applicant.

Date Mailed: July 5, 2007

Sheet 1 of 3

<b>FORM 1449 O P E INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (use several sheets if necessary)</b> <i>WIL 09 2007</i>	Docket Number: 10467.43US12	Application Number: 10/751,091
	Applicant: MOECKLY ET AL.	
	Filing Date: 01/02/2004	Group Art Unit: 1754

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>PW</i>	4,916,116	04/10/1990	Yamazaki			
	4,943,558	07/24/1990	Soltis et al.			
	5,077,270	12/31/1991	Takeda et al.			
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	5,892,243	04/1999	Chan			
	5,904,861	05/1999	Ban et al.			
FOREIGN PATENT DOCUMENTS						
	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES
	0 521 765 A2	01/07/1993	EP			
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<i>PW</i>		"Poster Sessions", Source Unknown, pg. 109 (1994)				
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EXAMINER <i>PW</i>	DATE CONSIDERED <i>9/17/07</i>
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FORM 1449*		Docket Number:	Application Number:
INFORMATION DISCLOSURE STATEMENT		10467.43US12	10/751,091
IN AN APPLICATION		Applicant: MOECKLY ET AL.	
(Use several sheets if necessary)		Filing Date: 01/02/2004	Group Art Unit: 1754

<i>RW</i>	Hunt, B. et al., "High Temperature Superconductor Josephson Weak Links", <i>Second Symposium on Low Temperature Electronics and High Temperature Superconductivity, Electrochemical Society Meeting, Honolulu, Hawaii</i> , Vol. 93-22, pp. 467-472 (May 1993).
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EXAMINER <i>Bal Watan</i>	DATE CONSIDERED <i>7/17/07</i>
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Date Mailed: July 5, 2007

Sheet 3 of 3

FORM 1449*		Docket Number: 10467.43US12	Application Number: 10/751,091
INFORMATION DISCLOSURE STATEMENT  IN AN APPLICATION  (Use several sheets if necessary)		Applicant: MOECKLY ET AL.	
		Filing Date: 01/02/2004	Group Art Unit: 1754

<i>PW</i>		Yoshida, J., "Recent Progress of High-Temperature Superconductor Josephson Junction Technology for Digital Circuit Applications," <i>IEICE Trans. Electron.</i> , Vol. E83-C, No. 1, pp. 49-59 (January 2000).
<i>J</i>		Yoshida, J. et al., "Current transport in interface-engineered high-T <sub>c</sub> Josephson junctions," <i>Physica C</i> , Vol. 367, pp. 260-266 (2002).
<i>J</i>		Yoshida, J. et al., "Interface-engineered Junctions with YBaCuO as the Counter-electrode," pp. 1-5 (2002).
<i>✓</i>		Yoshitake, T. et al., "Effect of Oxygen Plasma Annealing on Superconducting Properties of Bi <sub>2</sub> (Sr,Ca) <sub>3</sub> Cu <sub>2</sub> O <sub>x</sub> and YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> Thin Films", <i>Appl. Phys. Lett.</i> , Vol. 56, No. 6, pp. 575-577 (February 5, 1990)

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PATENT TRADEMARK OFFICE

EXAMINER	<i>Paul Weller</i>	DATE CONSIDERED	<i>7/17/07</i>
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